

Invitation List for IEUVI Mask Technical Working Group - 8155

Last Name	First Name	Company
Kimmel	Kurt	Advanced Mask Technology Center
Holfeld	Christian	Advanced Mask Technology Center
La Fontaine	Bruno	Advanced Micro Devices
Wood	Obert	Advanced Micro Devices
Zurbrick	Larry	Agilent Technologies
Le Guet	Catherine	Alcatel Vacuum Technology France
Peters	Jan Hendrik	AMTC
Ikuta	Yoshiaki	Asahi Glass Co. Ltd.
Kikugawa	Shinya	Asahi Glass Company
Matsumoto	Katsuhiko	Asahi Glass Company
Groeneveld	Rogier	ASML
Harned	Noreen	ASML
Zimmerman	John	ASML
Gordon	Tom	ASYST
Tobeas	Stephen	Brooks Automation
Gomei	Yoshio	Canon Inc.
Ware	Phil	Canon USA
Hartley	John	CNSE - SUNY
Navan	David	Corning
Beall	Lorrie	Corning Incorporated
Sell	Bob	Corning Incorporated
Mueller	Michael	Corning Incorporated
Yokoyama	Junichi	Corning International K.K.
Sano	Hisatake	Dai Nippon Printing Co.
Abe	Tsukasa	Dai Nippon Printing Co.
Hayashi	Naoya	Dai Nippon Printing Co.,Ltd.
Halbmaier	Dave	Entegris Inc.
Abe	Naomichi	EUVA
Ogawa	Masashi	EUVA
Ahn	Jinho	Hanyang University
Sengoku	Masayuki	Hitachi High Tech.
Matsuoka	Genya	Hitachi High-Technologies
Nagarekawa	Osamu	HOYA Corporation
Shimajima	Shoji	HOYA CORPORATION
Shoki	Tsutomu	HOYA Corporation
Lercel	Michael	IBM
Racette	Ken	IBM
Jonckheere	Rik	IMEC
Jonckheere	Rik	IMEC
He	Long	Intel
Hoshino	Eiichi	Intel
Yan	Pei-yang	Intel
Vandentop	Gilroy	Intel
Orvek	Kevin	SEMATECH
Yamamura	N.	JEOL
Dilorenzo	Matt	KLA-Tencor
Bareket	Noah	KLA-Tencor
Chang	Alex	KLA-Tencor
Grady	Edward	KLA-Tencor
Asai	Hiroshi	Laseretec Corporation

Iwasaki	Yutaka	Laseretec Corporation
Okabayashi	Osamu	Lasertec
Gullikson	Eric	Lawrence Berkeley National Lab
Terasawa	Tsuneo	MIRAI-ASET
Suzuki	Kazuaki	Nikon corporation
Hagiwara	Tsuneyuki	Nikon corporation
Sogard	Michael	Nikon Research Corporation of America
Yoshitake	Shusuke	NuFlare Technology Inc.
Rody	Yves	NXP
Nakajima	Toshihide	Ohara
Proglar	Chris	Photronics
Kamm	Frank-Michael	Qimonda
Wurm	Stefan	SEMATECH
Cha	Byung Cheol	Samsung
Cho	Sung Yong	Samsung
Han	Hakseung	Samsung
Kim	Dongwan	Samsung
Kim	Seong Sue	Samsung
Kim	Byung-Gook	Samsung
Yoon	Gi Sung	Samsung
Eynon	Ben	Samsung
Jeon	Chan-Uk	Samsung
Ota	Kazuya	Selete
Suga	Osamu	Selete
Yamabe	Masaki	Selete
Nishiyama	Iwao	SELETE
Mori	Ichiro	SELETE
Shigemura	Hiroyuki	SELETE
Taguchi	Takao	SELETE
Kells	Beth	SEMATECH
Margiotta	Judi	SEMATECH
Seidel	Phil	SEMATECH
Orvek	Kevin	SEMATECH
Yamada	Motoyuki	Shin-Etsu Chemical
Nakamura	Yoshihiro	SOL Corporation
Miyajima	Toshihiko	TDK Corporation
Nishiyama	Yasushi	Toppan Printing Co.
Higashikawa	Iwao	Toshiba
Mitsui	Soichiro	Toshiba
Higashikawa	Iwao	Toshiba
Asano	Mutsumi	TOSOH
Kondo	Shinichi	TOSOH SGM
Dai	Chang-Ming	TSMC
Engelstad	Roxann	University of Wisconsin - Madison
Randive	Rajul	Veeco Instruments, Inc.
Edinger	Klaus	Zeiss SMT

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Total Registered

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